

00862.109138.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

NOV 2 9 2006

In re Application of:

Examiner: Andy Huynh

YOSHINOBU SEKIGUCHI, et al.

Group Art Unit: 2818

Application No.: 10/566,170

371(c) Date: January 27, 2006

Int'l. Filing Date: June 15, 2005

For: SEMICONDUCTOR FILM)
MANUFACTURING METHOD :

AND SUBSTRATE)

MANUFACTURING METHOD : November 28, 2006

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents, other than the U.S. patent documents, are enclosed.

Japan 2004-119807, Japan 2003-78117, Japan 2002-280531, and Japan 2001-192300 were cited in the International Search Report and/or Written Opinion which issued in the corresponding international application. A copy of the International Search Report and a copy of the Written Opinion are enclosed.

The following documents are discussed at the following pages of the specification:

<u>Documents</u>	Page(s)
U.S. 6,559,075	1
U.S. 6,071,795	1
Japan 3518455	1
O. Ambacher, et al., Materials Research Society Symposium Proceedings, Vol. 617, 2000, pp. J1.7.1-J1.7.12	1
W. S. Wong, et al., Applied Physics Letters, Vol. 75, No. 10, September 6, 1999, pp. 1360-1362	1-2
Daisuke Morita, et al., Japanese Journal of Applied Physics, Vol. 41, Pt. 2, No. 12B, 2002, pp. L1434-L1436	2

English-language abstracts for the Japanese documents are also enclosed.

This Information Disclosure Statement is being filed before the issuance of a first Office Action on the merits. Therefore, no fee under 37 C.F.R. § 1.97(c)(2) is believed due. Nevertheless, the Commissioner may charge Deposit Account No. 06-1205, should any fee be due for filing this paper.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be initialed and returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Costa Mesa,

California office at (714) 540-8700. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,

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FORM PTO 1449 (modified)			ATTY DOCKET NO. 00862.109138.	APPLICATION NO. 10/566,170			
U.S. DEPARTMENT OF COMMERCE OIPE		APPLICANT					
LIST OF REFE	RENCES CITED BY APPLI	CANT(S)	YOSHII	NOBU SEKIGL	JCHI, et al.		
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) NOV 2 9 2006		371(c) DATE		GROUP			
*EXAMINER DOCUMENT			January 27, 2006		2818		
	12	The Still	U.S. PATENT DOCUMENTS				
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	6,559,075	05/06/03	Kelly, et al.	438	795		
	6,071,795	06/06/00	Cheung, et al.	438	458		
		FC	REIGN PATENT DOCUMENTS				
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT	
	2004-119807	04/15/04	Japan			Abstract	
	3518455	02/06/04	Japan			Abstract	
	2003-78117	03/14/03	Japan			Abstract	
	2002-280531	09/27/02	Japan			Abstract	
	2001-192300	07/17/01	Japan			Abstract	
	0	THER DOCUMENT(S) (Including Author, Title, Date, Pertinen	nt Pages, Etc.)			
O. Ambacher, et al., "Laser-Induced Liftoff and Laser Patterning of Large Free-Standing GaN Substrates", Materials Research Society Symposium Proceedings, Vol. 617, 2000, pp. J1.7.1-J1.7.12.							
	Daisuke Morita, et al., "High Output Power 365 nm Ultraviolet Light Emitting Diode of GaN-Free Structure", Japanese Journal of Applied Physics, Vol. 41, Pt. 2, No. 12B, 2002, pp. L1434-L1436.						
	W. S. Wong, et al., "Fabrication of thin-film InGaN light-emitting diode membranes by laser lift-off", Applied Physics Letters, Vol. 75, No. 10, September 6, 1999, pp. 1360-1362.						
EXAMINED	I int-on , Applie	u i ilysics Let	DATE CONSIDERED		, pp. 1000310		

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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